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PTO/SB/05A(10-01)  
Approved for use through 10/31/2002, OMB 651-0001  
US Patent & Trademark Office, U.S. DEPARTMENT OF COMMERCE

Complete if Known

Application Number	09/484303
Filing Date	January 18, 2000
First Named Inventor	Ahn, Kie
Group Art Unit	2823
Examiner Name	Berezny, Neal

Attorney Docket No: 303.648US1

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 Examiner Name Berezny, Neal

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Sheet 3 of 3

Attorney Docket No: 303.648US1

Examiner Initials*	Cite No <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), date of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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